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	Application No.	Applicant(s)	•
Madia a RAU a a L. 114	09/774,921	SHIRAISHI, HIDEAKI	
Notice of Allowability	Examiner	Art Unit	
	Dung Nguyen	2871	
The MAILING DATE of this communication appear All claims being allowable, PROSECUTION ON THE MERITS IS (herewith (or previously mailed), a Notice of Allowance (PTOL-85) of NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIC of the Office or upon petition by the applicant. See 37 CFR 1.313	OR REMAINS) CLOSED in or other appropriate commi GHTS. This application is s	n this application. If not includ unication will be mailed in due	ed course. THIS
1. This communication is responsive to 07/30/2004.			
2. ☑ The allowed claim(s) is/are <u>1-4</u> .			
3. $igotimes$ The drawings filed on <u>31 January 2001</u> are accepted by the	Examiner.		
4. Acknowledgment is made of a claim for foreign priority und a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received:	been received. been received in Application uments have been received if this communication to file ENT of this application. ted. Note the attached EXA is reason(s) why the oath of be submitted. on's Patent Drawing Review Amendment / Comment of the header according to 37 CF it of BIOLOGICAL MATE	on No In this national stage applicated in this national stage applicated in this national stage applicated are reply complying with the reconstruction of the drawings in the front (not the R 1.121(d).	quirements IOTICE OF
Attachment(s) 1. Notice of References Cited (PTO-892) 2. Notice of Draftperson's Patent Drawing Review (PTO-948) 3. Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No./Mail Date 4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ☐ Interview S Paper No./ 7. ⊠ Examiner's	formal Patent Application (PT0 ummary (PTO-413), /Mail Date Amendment/Comment Statement of Reasons for Allo	,

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DETAILED ACTION

Applicant's amendment dated 07/30/2004 has been received and entered. By the amendment, claims 1-4 are remain pending in the application.

Examiner's Amendment

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

In view of the Examiner's restriction requirement and subsequent election dated 04/30/2003 without traverse, claims 5-11 have been withdrawn from consideration, and they are now canceled by this Examiner's amendment.

Reasons for Allowance

- 2. Claims 1-4 are allowed.
- 3. The following is an examiner's statement of reasons for allowance:

None of the prior art of record suggests or discloses alone or in combination that a method of fabricating a liquid crystal display substrate comprising the step of forming at least two scribe cracks only on a second face of a first sheet and only on the first face of a second sheet, said at least two scribe cracks intersecting each other on the second face of the first sheet and intersecting each other on the first face of the second sheet, adhering the two sheets of substrates to each other so that said faces on which said

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scribe cracks are formed oppose each other via a seal layer disposed so as to enclose an area, on which a liquid crystal layer is scheduled to be formed, and via a dummy seal layer disposed to prevent bias of stress when cutting the substrate and cutting the adhered substrate as set forth in claim 1.

The most relevant reference, the combination of Nakahara et al (US 6,239,855) and Shishido et al (JP 9-311323), fail to disclose or suggest a step of forming at least two scribe cracks only on a second face of a first sheet and only on the first face of a second sheet and then adhering the two sheets of substrates to each other so that said faces on which said scribe cracks are formed oppose each other via a seal layer disposed so as to enclose an area, on which a liquid crystal layer is scheduled to be formed. The combination of Nakahara and Shishido reference disclose a method of providing a scribe line on both inner and outer faces of a pair of sheets before cutting.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Dung Nguyen whose telephone number is 571-272-2297. The examiner can normally be reached on Monday-Thursday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Robert H. Kim can be reached on 571-272-2293. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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